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Spectrometer Application Report

Brillouin Spectroscopy of a Silicon Wafer

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Figure 1 shows the Brillouin spectrum of a silicon wafer, acquired using a camera cooled only at -5°C, limiting the exposure time to 10 seconds because of the dark current. The spectrum was averaged 50 times (thus accumulating the noise associated with 50 read-out events). A deeper cooled camera will be used in future work to allow for longer exposure time, which will result in a much higher signal-to-noise ratio with only a few minutes of total exposure. Nevertheless, even with a short exposure time, the spectrum in Figure 1 shows the great potential of the system.

The measured Brillouin frequency shift of the silicon wafer is 131.46 ± 0.07 GHz, in agreement with the expected shift. The pump laser signal is greatly attenuated (>70 dB) by the two "Pump Killers" included in the systems.

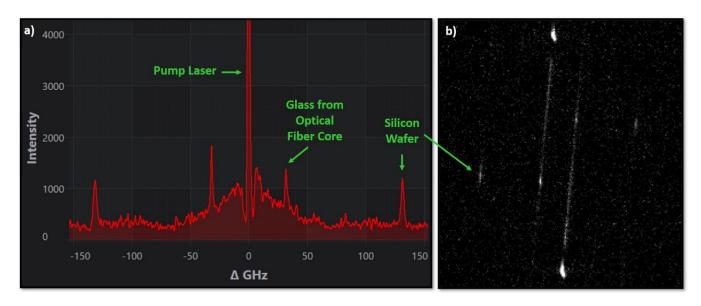


Figure 1: a) Brillouin frequency shift spectrum of a silicon wafer, acquired with a camera cooled only at -5°C. b) Raw sensor image. The exposure time was set to 10 seconds and the number of averages to 50.

Specifications

Sample	System
 Material: single crystal silicon wafer The expected Brillouin frequency shift of silicon is around 131.6 GHz (using a longitudinal speed of sound in silicon of 8433 m/s, a refractive index of 4.151, and a pump wavelength of 532.2 nm) 	 Pump wavelength: 532.2 nm Power at sample: 25 mW Excitation/collection with 20X objective FWHM of the instrument response: nominal 0.9 GHz Repeatability of Brillouin shift: highly sample and exposure dependent; < 10 MHz is possible